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(71) Applicant (for all designated States except US):
NANOFACTORY INSTRUMENTS AB [SE/SE];
Walleriusgatan 2, S-412 58 Göteborg (SE).

(72) Inventors; and

(75) Inventors/Applicants (for US only): **ENOKSSON, Peter**
[SE/SE]; Småtuvegatan 7, S-431 69 Mölndal (SE). **NA-**
FARI, Alexandra [SE/SE]; Eklandagatan 33, S-412 82
Göteborg (SE). **OLIN, Håkan** [SE/SE]; Kyrkogatan 10,
S-852 31 Sundsvall (SE). **ALTHOFF, Fredrik** [SE/SE];
Törnrosavägen 8, S-435 31 Mölnlycke (SE). **DANILOV,**

Andrey [RU/SE]; Nanofactory Instruments AB, Wallerius-
gatan 2, S-412 58 Göteborg (SE). **DAHLSTRÖM, Jens**
[SE/SE]; Royens Gata 1, S-431 34 Mölndal (SE).

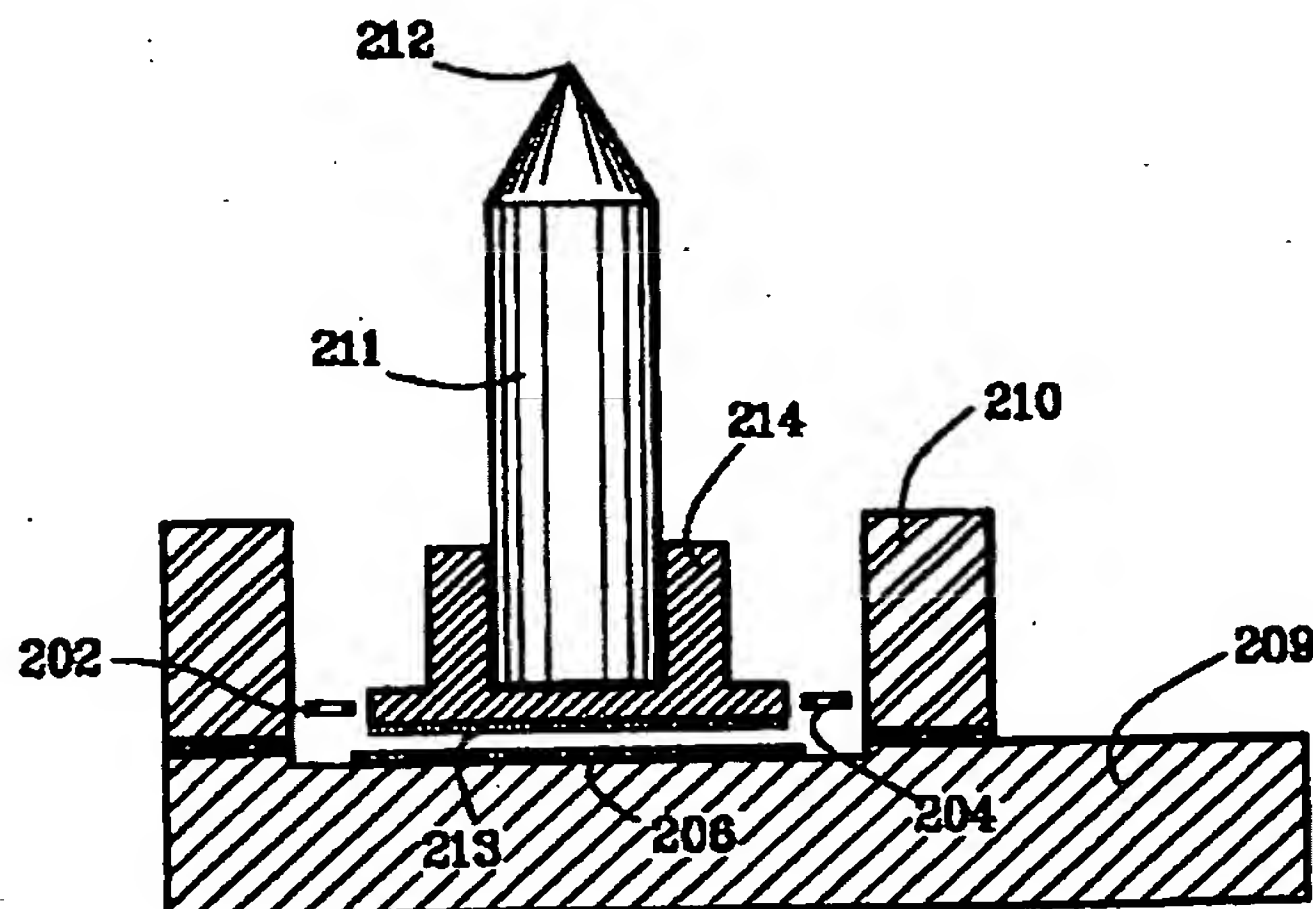
(74) Agent: **VALEA AB;** Lindholmsspiren 5, S-417 56 Göte-
borg (SE).

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(54) Title: MEMS NANOINDENTER



(57) Abstract: A force sensor (200) and nanoindentation system (300) using such force sensor (200), wherein the force sensor (200) comprise a movable membrane (207) attached to a fixed bulk structure (210) with springs (201, 202, 203, 204) formed between the membrane (207) and bulk structure (210); the springs (201, 202, 203, 204) may be provided two on each side of a rectangular membrane (207) and each in the form of a U-shape with displacing elements (801) formed perpendicular to each open end of each U-shaped spring (800). The force sensor further comprises electrodes (206) for detecting capacitive changes between the movable membrane (207) and the electrodes (206) in order to measure a movement in relation to an applied force. The membrane (207) further comprises a probe holding structure (214) for providing a solution for interchangeable probes (211).

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